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Notice of Allowability	Application No.	Applicant(s)
	10/624,340	MCCLURE ET AL.
	Examiner	Art Unit
	Nguyen T. Ha	2831
The MAILING DATE of this communication appeal all claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in this ap or other appropriate communication IGHTS. This application is subject t	plication. If not included n will be mailed in due course. THIS
2. The allowed claim(s) is/are 1,5-41,52,55-63 and 71-78.		
3. Acknowledgment is made of a claim for foreign priority unall All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received: Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 4. A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give 5. CORRECTED DRAWINGS (as "replacement sheets") must (a) including changes required by the Notice of Draftspers 1) hereto or 2) to Paper No./Mail Date	e been received. e been received in Application No cuments have been received in this of this communication to file a reply fENT of this application. itted. Note the attached EXAMINER es reason(s) why the oath or declarate st be submitted. son's Patent Drawing Review (PTO) . s Amendment / Comment or in the 0	national stage application from the complying with the requirements R'S AMENDMENT or NOTICE OF ation is deficient. -948) attached Office action of
Identifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in the second of the sheet of the she	he header according to 37 CFR 1.1216 sit of BIOLOGICAL MATERIAL	(d). must be submitted. Note the
Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☑ Information Disclosure Statements (PTO/SB/08), Paper No./Mail Date <u>6763</u> ★ 1205. 4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material	5. Notice of Informal F 6. Interview Summary Paper No./Mail Da 7. Examiner's Amenda 8. Examiner's Statemen	(PTO-413), ite

PHIMAH EXAMINER

U.S. Patent and Trademark Office PTOL-37 (Rev. 08-06)

Notice of Allowability

Part of Paper No. Mail Date 1

DETAILED ACTION

Response to Arguments

1. The applicant's argument that Moradi et al. failed to disclose a capacitor construction comprising an insulative nitride layer between a first electrode and a surface supporting the capacitor construction. The examiner finds this argument persuasive. Therefore, the examiner made decision to allow this limitation over the prior art of record.

Allowable Subject Matter

2. Claims 1, 5-41, 52, 55-63, and 71-78 are allowed.

The following is an examiner's statement of reasons for allowance:

With respect to claims 1,5, 8-11, 52, 55, 57-58, 71-72 and 75-76 the prior art alone or in combination does not teach the limitation of a capacitor construction comprising a conductive nitride layer between a first electrode being in conductive contact with the nitride layer, and a second electrode over the capacitor dielectric, the capacitor construction exhibiting a lower RC time constant compared to an otherwise identical capacitor construction lacking the conductive nitride layer.

With respect to claims 6,7, 12, and 56, the prior art alone or in combination does not teach the limitation of a capacitor construction comprising an insulative nitride layer between a first electrode and a surface supporting the capacitor construction, a capacitor dielectric over the first electrode.

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With respect to claims 13-23, the prior art alone or in combination does not teach the limitation of a capacitor construction comprising: a rough silicon layer, a nitride layer under the rough silicon layer, a capacitor dielectric over the rough silicon layer.

With respect to claims 24-33, the prior art alone or in combination does not teach the limitation of a capacitor construction comprising: a conductive rough silicon layer over a support surface, a nitride layer between the rough silicon layer and the support surface, a first electrode comprising the rough silicon layer.

With respect to claims 34-41, the prior art alone or in combination does not teach the limitation of a capacitor construction comprising: a composite first electrode comprising a first conductive layer over and in conductive contact with the storage node and comprising a conductive polysilicon layer over and in conductive contact with the first conductive layer, the first conductive layer exhibiting a first conductivity greater than a second conductivity of the polysilicon layer.

With respect to claims 59-63, the prior art alone or in combination does not teach the limitation of a capacitor construction forming method comprising: forming a conductive polysilicon layer over and in conductive contact with the first conductive layer, the first conductive layer exhibiting a first conductivity greater than a second conductivity of the polysilicon layer and the first conductive layer and polysilicon layer being comprised by a composite first electrode.

With respect to claims 73-74 and 77-78, the prior art alone or in combination does not teach the limitation of a memory device comprising: a composite first electrode comprising a first conductive layer over and in conductive contact with the storage node

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and a conductive polysilicon layer over and in conductive contact with the first conductive layer, the first conductive layer exhibiting a first conductivity greater than a second conductivity of the polysilicon layer.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Citation Relevant of Prior Art

- 3. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure.
 - a. Kijima et al. (US 6,563,691) disclose mounting structure for capacitors.
- b. Le et al. (US 6,262,469) disclose capacitor for use in a capacitor divider that has a floating gate transistor as a corresponding capacitor.
 - c. Embree (US 5,187,637) discloses monolithic high-voltage capacitor.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Nguyen T. Ha whose telephone number is 571-272-1974. The examiner can normally be reached on Monday-Friday from 8:30AM to 6:00PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Dean Reichard can be reached on 571-272-2800 ext. 31. The fax phone

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number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

NGUYEN T. HA PRIMARY EXAMINER

June 15, 2007